# ICP SPTS

# SOP

STANDART OPERATION PROCEDURE

## by Alex Yoffe

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|---|---|---|
| **1** | **Log** in to system by pressing the logged user on the upper left corner. |  |
| 2 | Press the transport button |  |
| **3** | Bring the Load Lock to atmosphere by pressing the vent and open the Load Lock lid.<br>Place a wafer on the End Effector | Vent<br> |
| **4** | Close the lid and run a **PUMP** sequence to pump the Load Lock to vacuum |  |
| 1 | | |

| | | |
|---|---|---|
| **5** | **Click Load and Ok to transfer sample to process chamber** |  |
| **6** | **Click to process chamber Icon** |  |
| **7** | **Click on Rapier Icon, choose Process, click Ok**<br><br>One process has completed run the **UNLOAD** sequence with the wafer returned to the load lock, run **VENT** sequence from the ???<br>With the load lock atmosphere, open the load lock lid. Remove the wafer**.**<br><br><br>**Note :**<br>**The colors of the icons in the windows provide status information as follows:**<br>\***grey**-circle in the middle of a module-module in Manual Mode<br>\***Blue area**-module in aotomatic mode but not progressing<br>**\*Green-**Busy; I.e proccessing or in-between states<br>**\*Red**-Aborted, message displayed on individual mimic.<br>**\*Orange**=Hold Fault, usually with a hold message on the individual mimic and at the top of control page<br>**\*Yellow**-warning Fault |  |

| 8 | Close the load lock door.<br>Click Pump and Ok | |
|---|---|---|
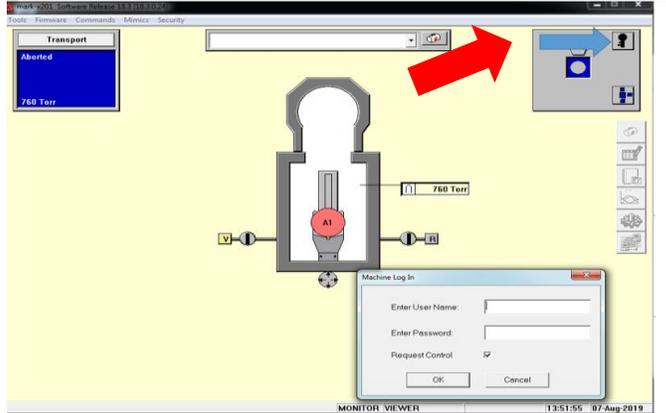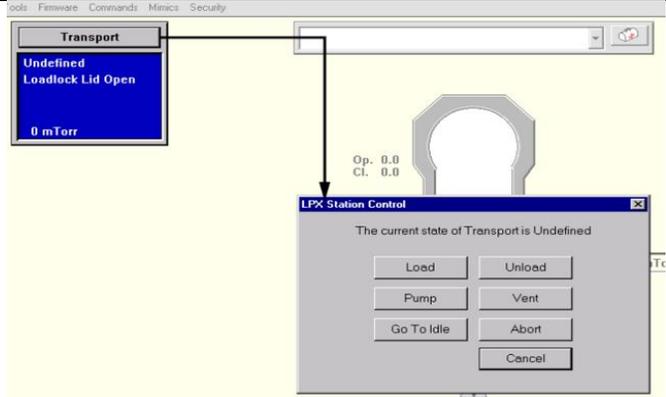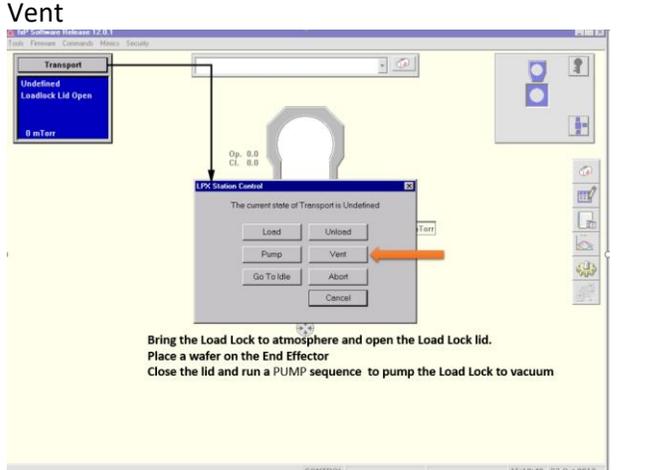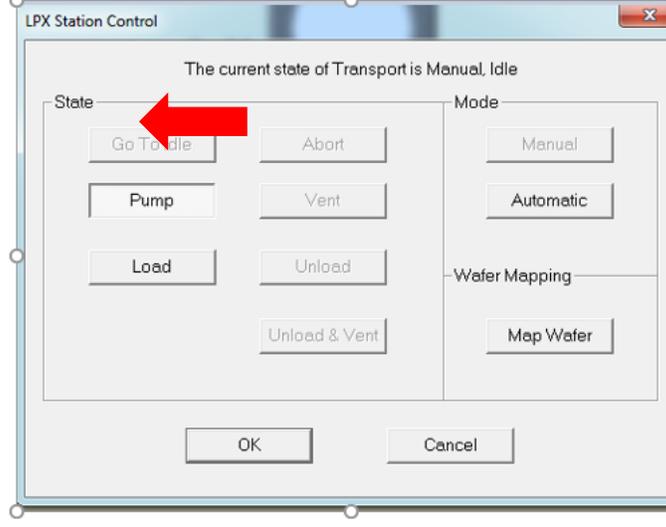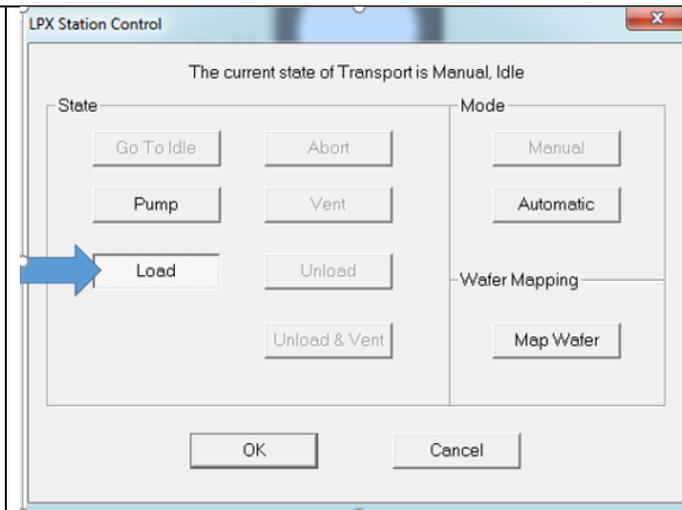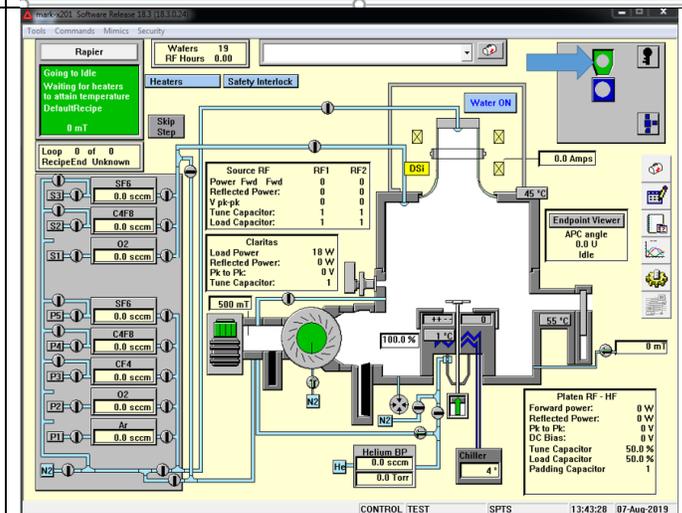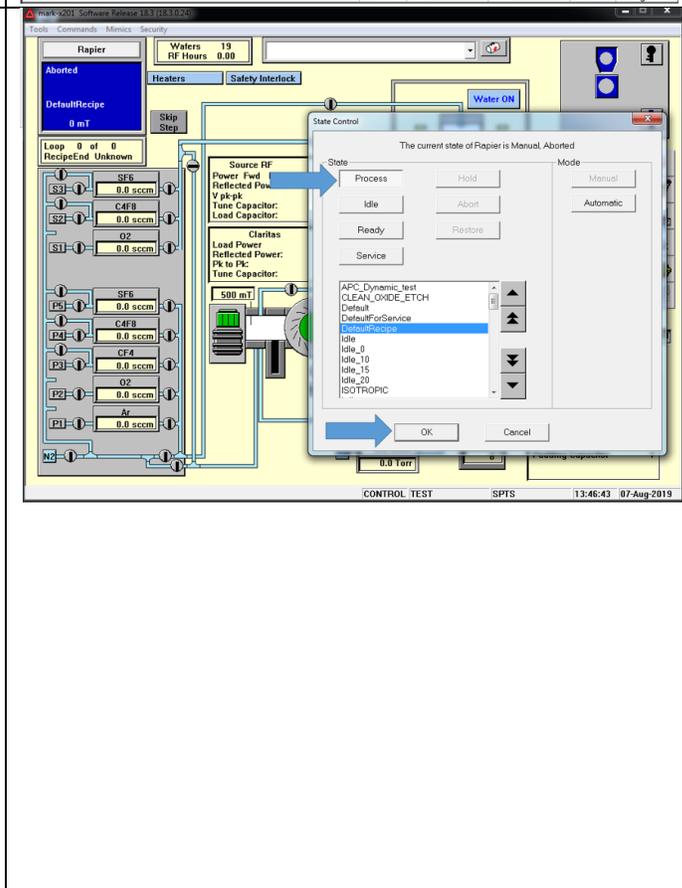
LPX Station Control

The current state of Transport is Manual, Idle

State
- Go To Idle
- Pump
- Load

- Abort
- Vent
- Unload

- Unload & Vent

Mode
- Manual
- Automatic

Wafer Mapping
- Map Wafer

OK          Cancel